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Leonard Forbes, et al.FILING DATE  
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## U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
K.N.	AA	6,246,076	06/01	Lipkin, et al.			

## FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AB							

## OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

K.N.	AC		S. Ogawa, et al.,	Silicon-Aluminum Oxynitride Composite Films Deposited by Reactive Ion Beam Sputtering.	IEEE 1999, pp. 775-778.
	AD				
	AE				
	AF				
	AG				
	AH				
	AI				
	AJ				

EXAMINER

K. Bremmigen

DATE CONSIDERED

12/24/03

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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